

MEMS & Nano technology

For the positioning of xy-stages for MEMS and nano technology, a **Laser Doppler Scale (LDS)** with multiple-pass optical arrangement can be used to achieve sub-nanometer resolution (Ap-1115 and Technical article #13). For more detailed description, and specifications click on the **Technical brochure LDS-1000**.

- [LDS-1000](#) Precision Linear Positioning
- [Ap1115](#)-- A multiple-pass optical adapter for high resolution in turbulent environment
- [Tech Article #13](#)-- A linear actuator system with 1-angstrom closed -loop control resolution and 50-milimeter travel range

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